

Supporting Information

Polymer Brushes via Surface-Initiated Electrochemically Mediated ATRP: Role of a Sacrificial Initiator in Polymerization of Acrylates on Silicon Substrates

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Additional Experimental Data

Table S1. Low ppm *se*ATRP of HEA.

Entry	t [h]	NaBr [mol / dm ³]	HEA /solvent [v/v]	[Cu ^{II} Br ₂ /TPMA] [ppm by wt.]	<i>E</i> _{app} (a) [mV]	conv. (b) [%]	DP _{theo}	DP _{app} (c)	<i>k</i> _p ^{app} (c) [h ⁻¹]	<i>k</i> _{red} ^{app} (d) [s ⁻¹]	<i>M</i> _{n,app} (e)	<i>M</i> _{n,th} (f)	<i>D</i> (e)
1	4.5	-	50/50	51	320 mV (<i>E</i> _{pc} = -80 mV)	27	270	274	0.099	0.0021	32 700	43 500	1.35
2	8	0.1	50/50	51	190 mV (<i>E</i> _{pc} = -80 mV)	22	220	220	0.040 (0.051) ^(c)	0.0016	27 600	35 000	1.63
3	4.5	-	25/75	26	180 mV (<i>E</i> _{pc} = -120 mV)	31	310	308	0.094	0.0018	37 100	48 700	1.86

General reaction conditions: T = 55 °C; *V*_{tot} = 70 mL; [HEA]₀ = 2.4 M; [EBiB]₀ = 4.8 mM (except entry 3: [EBiB]₀ = 2.4 mM); [TBAP]₀ = 0.2 M *se*ATRP under constant potential electrolysis (working electrode (WE) = Pt plate, counter electrode (CE) = Al wire (*l* = 10 cm, *d* = 1 mm), reference electrode (RE) = Ag/AgI/I⁻). ^(a) Applied potential (*E*_{app}) was selected based on cyclic voltammetry (CV) analysis of catalyst complex (Figure S1a-c, Supporting Information); ^(b) Monomer conversion and apparent propagation rate coefficients (*k*_p^{app}) were determined by NMR; ^(c) *k*_p^{app} value determined for 4h of reaction time; ^(d) *k*_{red}^{app} – apparent reduction rate coefficient determined from first order plot of current vs. time (Figure S6a-c, Supporting Information); ^(e) apparent *M*_n and *D* were determined by THF GPC with PS standards; ^(f) *M*_{n,th} = ([M]₀/[I]₀) × monomer conversion × *M*_{monomer} + *M*_{initiator}.

Table S2. Theoretical Al³⁺ concentration in solution and polymer by monomer conversion.

Entry	Entry	<i>Q</i> (a) (C)	<i>n</i> _{Al³⁺} (b) (mol × 10 ⁵)	[Al ³⁺] _{solution} (c) (ppm by wt.)	[Al ³⁺] _{polymer} (d) (ppm by wt.)	
according to Table 1	1	1	3.579	1.24	4.6	0.5
	2	2	6.585	2.27	8.5	0.8
	4	3	1.699	0.59	2.3	0.4
according to Table S1	1	4	0.579	0.20	3.2	0.4
	2	5	2.989	1.03	16.6	1.8
	3	6	1.835	0.63	10.4	0.8

^(a) The total passed charge was calculated by integration of the chronoamperometry (CA) area, that is, *Q* = *I* × *t*; ^(b) Theoretical amount of Al³⁺ in the reaction mixture was calculated from CA: *n*_{Al³⁺} = *Q*/*F*/3, where *F* = 96,485 C/mol; ^(c) The Al concentrations in the reaction mixture was calculated according to the equation defined as: [Al³⁺]_{solution} = [Al³⁺] × MW_{Al} / wt_{total} × 1,000,000; ^(d) The Al concentrations in pure polymer sample were determined by the monomer conversion, i.e., [Al³⁺]_{polymer} = [Al³⁺]_{solution}/*df* × monomer conversion, where *df* is dilute factor *df* = 4 (except entries 3: *df* = 2.5; for entries 4–5: *df* = 2).

Table S3. Calculation of Cu^I/Cu^{II} ratio for the preparation of polyacrylate brushes.

Entry	Entry	Entry	k_p^{app}	$[P_n^*]$	K_{ATRP}	$[P_n-Br]$	$[Cu^I]/[Cu^{II}]$	$[Cu^I TPMA^+]$	$[Br-Cu^{II} TPMA^+]$
			(a)	(a)	(b)	(M)	(c)	(%)	(%)
		(M)	(h ⁻¹)	($\times 10^9$)	($\times 10^7$)	(M)			
according to Table 1	1	1	0.107	8.49	1.30	0.0024	27	96.5	3.52
	4	2	0.058	4.60	1.30	0.0028	13	92.8	7.22
according to Table S1	1	3	0.099	7.86	1.30	0.0048	13	92.7	7.30
	2	4	0.040	3.17	1.30	0.0048	5	83.7	16.32
	3	5	0.094	7.46	1.30	0.0024	24	96.0	3.98

^(a) The radical concentration $[P_n^*]$ was calculated according to the equation defined as $[P_n^*] = \left(\frac{d\ln[M]}{dt}\right) (k_p)^{-1}$ [1], where $\frac{d\ln[M]}{dt}$ values were calculated from the first order kinetics plots (Figures S7, 1a and 2a) [2], $k_p = 3,500 \text{ M}^{-1}\text{s}^{-1}$ [3]. ^(b) $K_{ATRP} = 1.3 \times 10^{-8}$ was determined for the Cu^I/TPMA⁺ catalyst in methyl acrylate/acetonitrile 50/50 (v/v) at 50 °C [4]. ^(c) The Cu^I/Cu^{II} ratio was calculated according to the equation defined as $\frac{[Cu^I TPMA^+]}{[Br-Cu^{II} TPMA^+]} = \frac{[P_n^*]}{[P_n-Br]K_{ATRP}}$ [4].

Table S4. Calculation of Dead Chain Fraction (DCF).

Entry	Entry	Entry	$[P_n^*]$	$[D]$	$[P_n-Br]_0$	DCF	CEF
			(M $\times 10^9$)	(M $\times 10^4$)	(M)	(%)	(%)
according to Table 1	1	1	8.49	1.9	0.0024	7.9	92.1
	4	2	4.60	3.3	0.0028	11.8	88.2
according to Table S1	1	3	7.86	1.2	0.0048	2.5	97.5
	2	4	3.17	0.3	0.0048	0.7	99.3
	3	5	7.46	1.1	0.0024	4.5	95.5

^(a) The radical concentration $[P_n^*]$ was calculated according to the equation defined as $[P_n^*] = \left(\frac{d\ln[M]}{dt}\right) (k_p)^{-1}$ [1], where $\frac{d\ln[M]}{dt}$ values were calculated from the first order kinetics plots (Figure S7, 1a and 2a) [2], $k_p = 3.5 \cdot 10^3 \text{ M}^{-1}\text{s}^{-1}$ [3]. ^(b) The concentration of terminated chains $[D]$ was calculated according to the equation defined as $[D] = k_t [P_n^*]^2 t$ where t (denote reaction time) = s, $k_t = 1.2 \times 10^8 \text{ M}^{-1}\text{s}^{-1}$ was determined for the 2-hydroxyethyl acrylate at room temperature [5] (except entry 2: $k_t = 5.7 \times 10^8 \text{ M}^{-1}\text{s}^{-1}$ was determined for the *n*-butyl acrylate at 50 °C) [6]. ^(c) DCF = $\left(\frac{[D]}{[P_n-Br]_0}\right) \cdot 100\%$ [1]. ^(d) CEF = 100% - DCF.

Table S5. Experimental values of contact angles for synthesized polymer brushes and brominated silica wafer.

Entry (according to Table 1)	Experimental Values of Θ [°]					
	Water	Standard Deviation	Formamide	Standard Deviation	Diiodomethane	Standard Deviation
1	61.86	1.23	45.23	1.06	39.26	1.32
2	68.67	1.40	50.28	1.63	38.68	1.99
4	98.60	1.43	69.60	1.94	46.15	1.06
5 (Si-Br)	73.01	1.19	54.68	1.27	34.22	1.12

Table S6. Parameters of free surface energy (FSE) as calculated by Owens-Wendt and van Oss-Good methods for synthesized polymer brushes and brominated silica wafer.

Entry. (according to Table 1)	Parameters of FSE [mJ/m ²]							
	Owens-Wendt Method				van Oss-Good Method			
	Water-diiodomethane				Diiodomethane-formamide-water			
	γ_s	γ_s^d	γ_s^p	γ_s^{LW}	γ_{s^+}	γ_{s^-}	γ_s^{AB}	γ_s
1	46.36 (±0.09)	31.82 (±0.08)	14.54 (±0.05)	39.986 (±0.9)	0.329 (±0.003)	17.534 (±0.249)	4.806 (±0.044)	44.791 (±0.263)
2	43.68 (±0.13)	33.73 (±0.12)	9.95 (±0.04)	40.268 (±0.393)	0.161 (±0.002)	12.685 (±0.222)	2.858 (±0.034)	43.126 (±0.395)
4	37.23 (±0.08)	37.08 (±0.08)	0.152 (±0.001)	36.392 (±0.189)	0.0122 (±0.0001)	0.243 (±0.004)	0.109 (±0.001)	36.501 (±0.189)
5 (Si-Br)	44.03 (±0.08)	37.07 (±0.08)	6.96 (±0.03)	42.386 (±0.233)	0.00077 (±0.00001)	10.674 (±0.152)	0.182 (±0.001)	42.568 (±0.233)

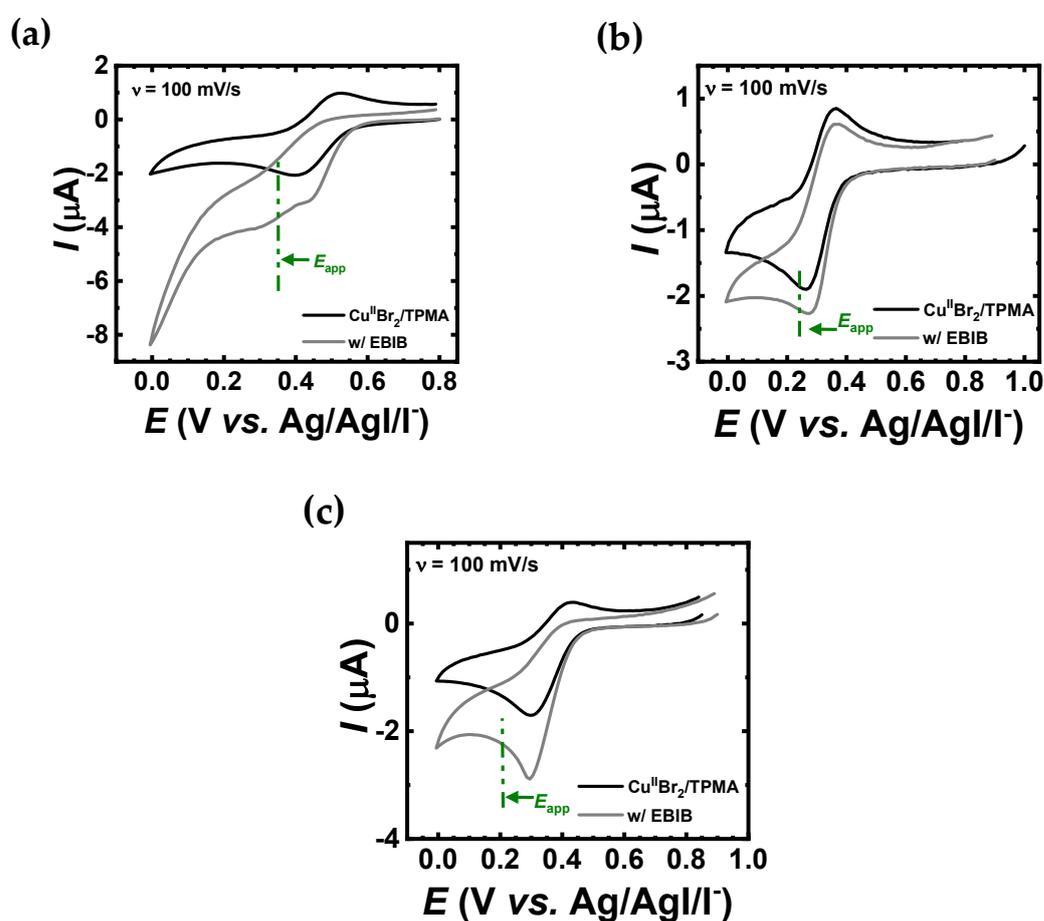


Figure S1. Cyclic voltammetry of Cu^{II}/Br₂/TPMA (black) and in the presence of EBiB (grey) according to (a) Table S1, entry 1, (b) Table S1, entry 2, and (c) Table S1, entry 3. The arrow (green) indicates the applied potential during electrolysis.

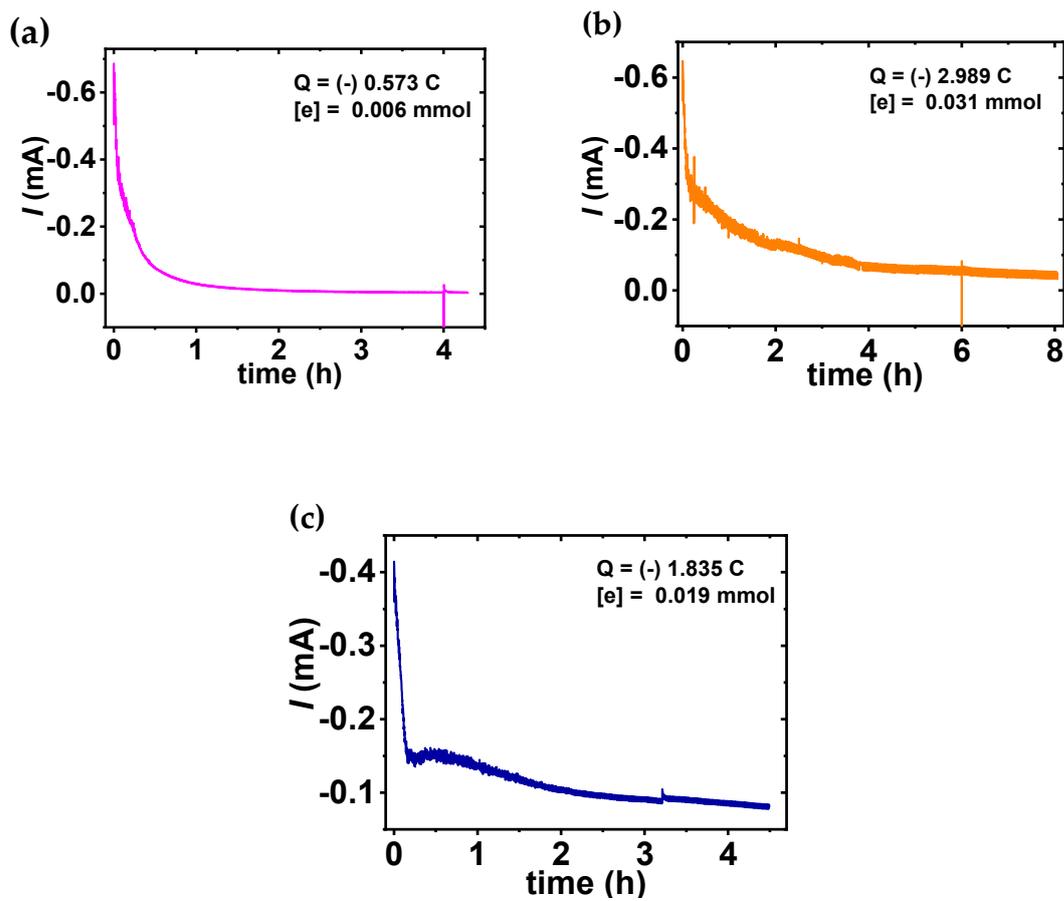


Figure S2. Current profile vs. polymerization time for the grafting of PHEA brushes from silica wafers *via* sacrificial initiator-assisted ultralow ppm SI-*se*ATRP according to (a) Table S1, entry 1, (b) Table S1, entry 2, and (c) Table S1, entry 3.

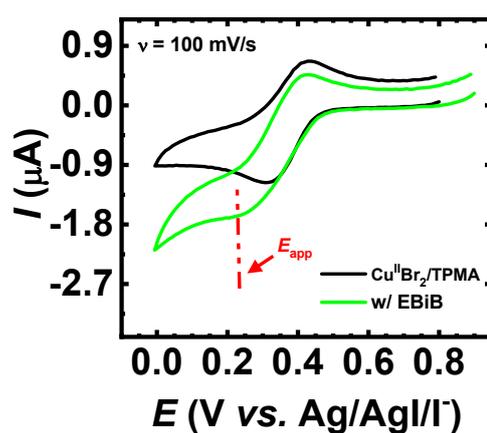


Figure S3. Cyclic voltammetry of $\text{Cu}^{\text{II}}\text{Br}_2/\text{TPMA}$ (black) and in the presence of EBiB (green). The arrow (red) indicates the applied potential during preparative electrolysis. Measurement conditions: $[\text{HEA}]_0/[\text{EBiB}]_0/[\text{Cu}^{\text{II}}\text{Br}_2]_0/[\text{TPMA}]_0 = 1000/1/0.05/0.10$, $[\text{HEA}]_0 = 2.2 \text{ M}$, $[\text{Cu}^{\text{II}}\text{Br}_2/\text{TPMA}]_0 = 0.12 \text{ mM}$, $[\text{TBAP}]_0 = 0.2 \text{ M}$. Table 1, entry 1.

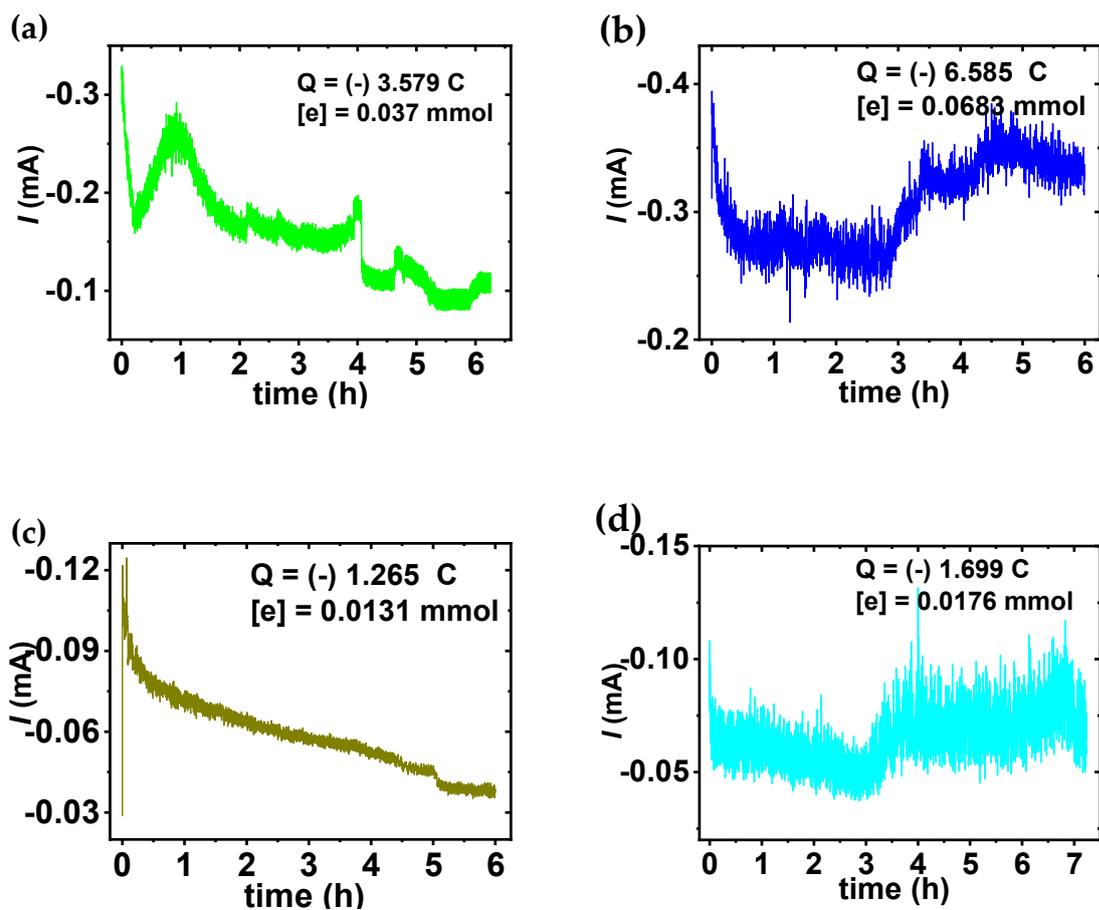


Figure S4. Current profile vs. time for the grafting of polymer brushes from silicon wafers according to (a) Table 1, entry 1, (b) Table 1, entry 2, (c) Table 1, entry 3, and (d) Table 1, entry 4.

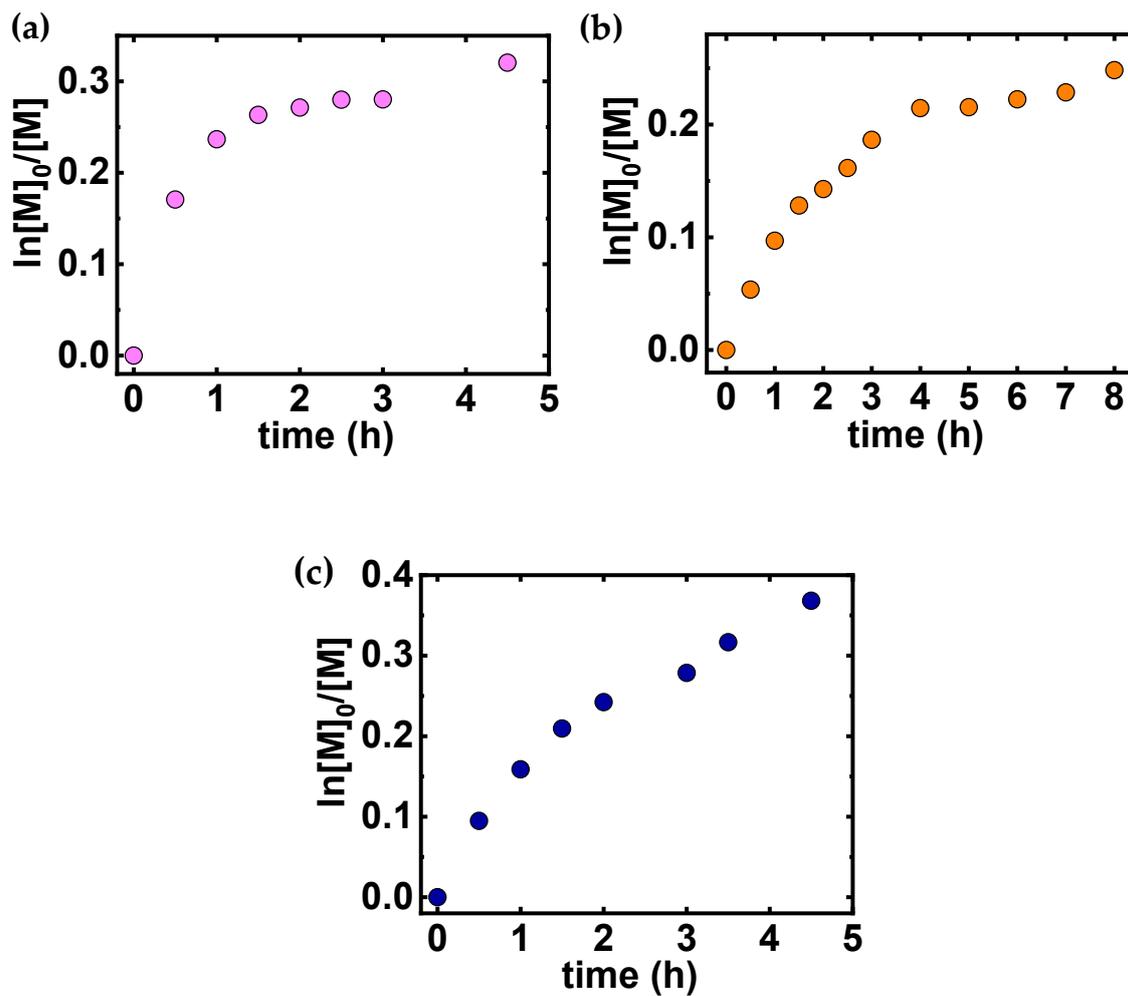


Figure S5. First-order kinetic plot of monomer conversion vs. polymerization time according to: (a) Table S1, entry 1, (b) Table S1, entry 2, and (c) Table S1, entry 3.

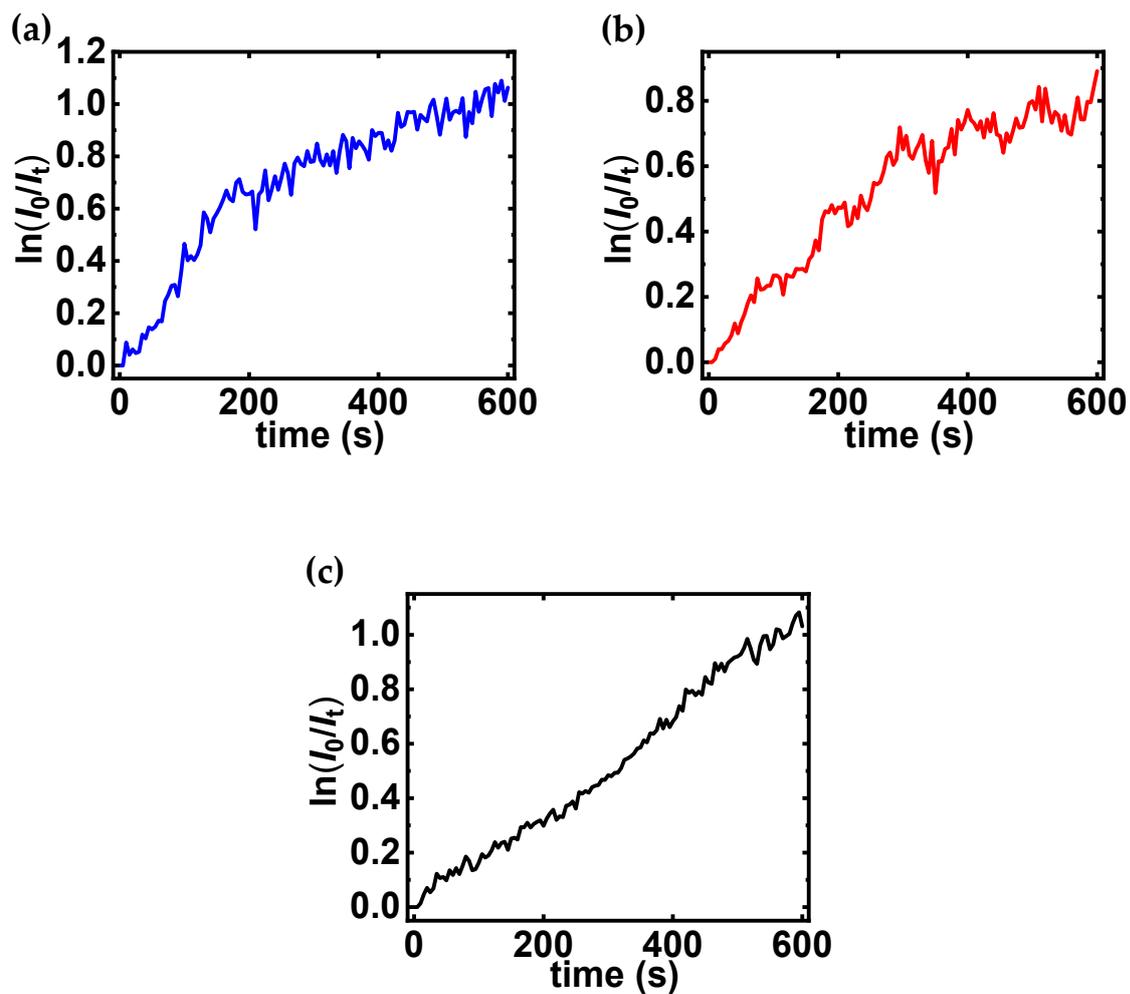


Figure S6. First-order plot of current vs. polymerization time for the grafting of PHEA brushes from silicon wafers via sacrificial initiator-assisted ultralow ppm SI-*se*ATRP according to (a) Table S1, entry 1, (b) Table S1, entry 2, and (c) Table S1, entry 3.

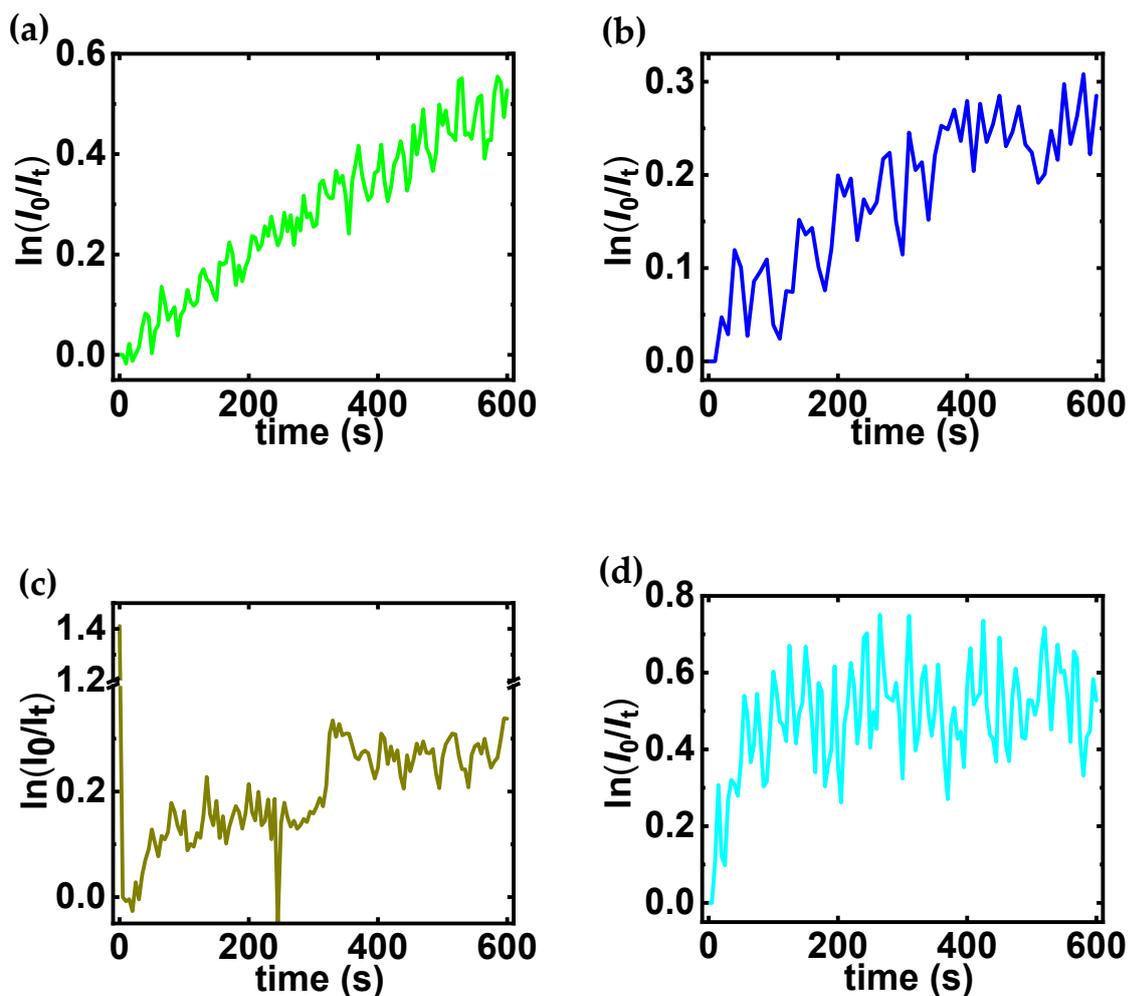


Figure S7. First-order plot of current *vs.* polymerization time for the grafting of polymer brushes from silicon wafers according to (a) Table 1, entry 1, (b) Table 1, entry 2, (c) Table 1, entry 3 and (d) Table 1, entry 4.

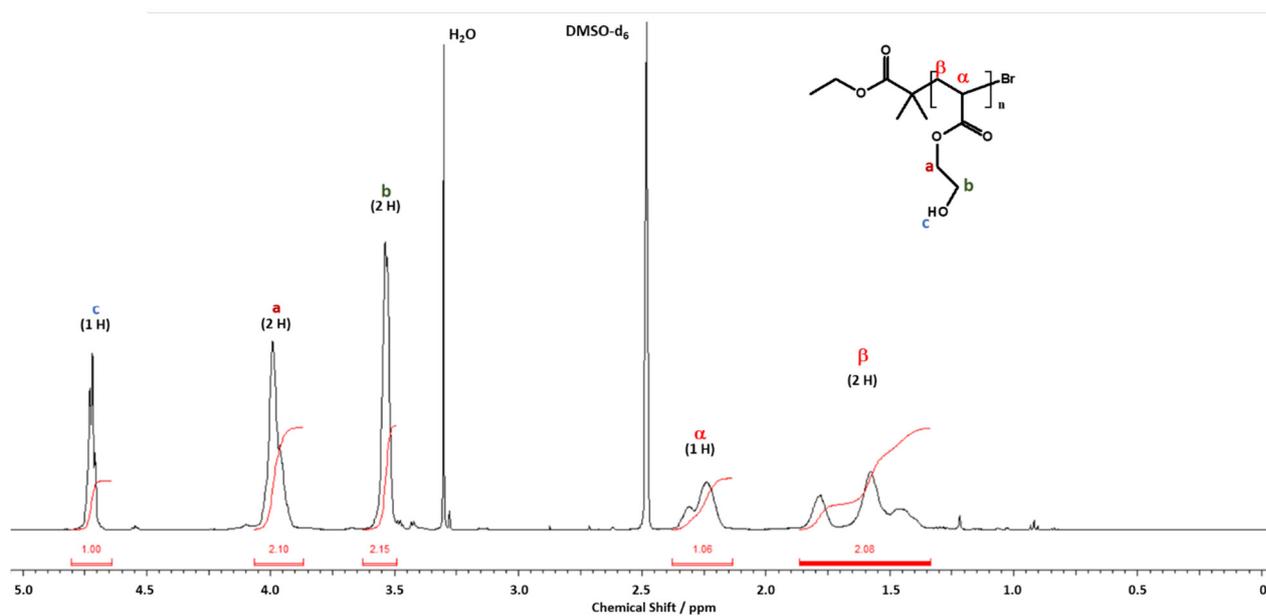


Figure S8. NMR spectrum of PHEA homopolymer (Table 1, entry 1).

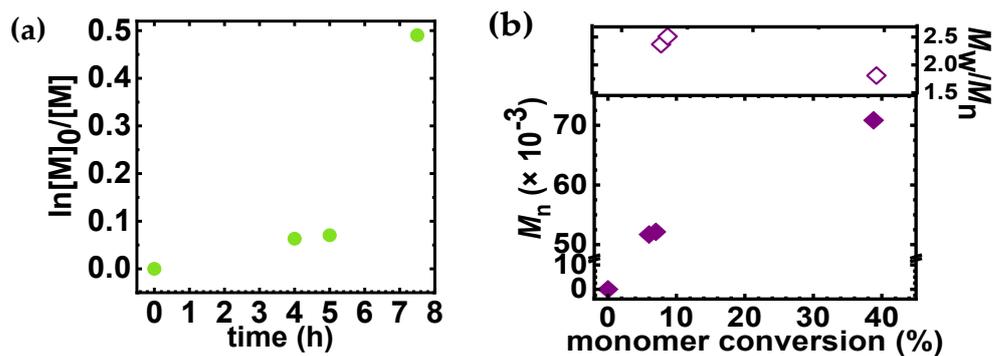


Figure S9. Synthesis of well-defined PBA chains generated in the solution: (a) First-order kinetic plot of monomer conversion *vs.* polymerization time, (b) M_n and M_w/M_n *vs.* monomer conversion. Table 1, entry 4.

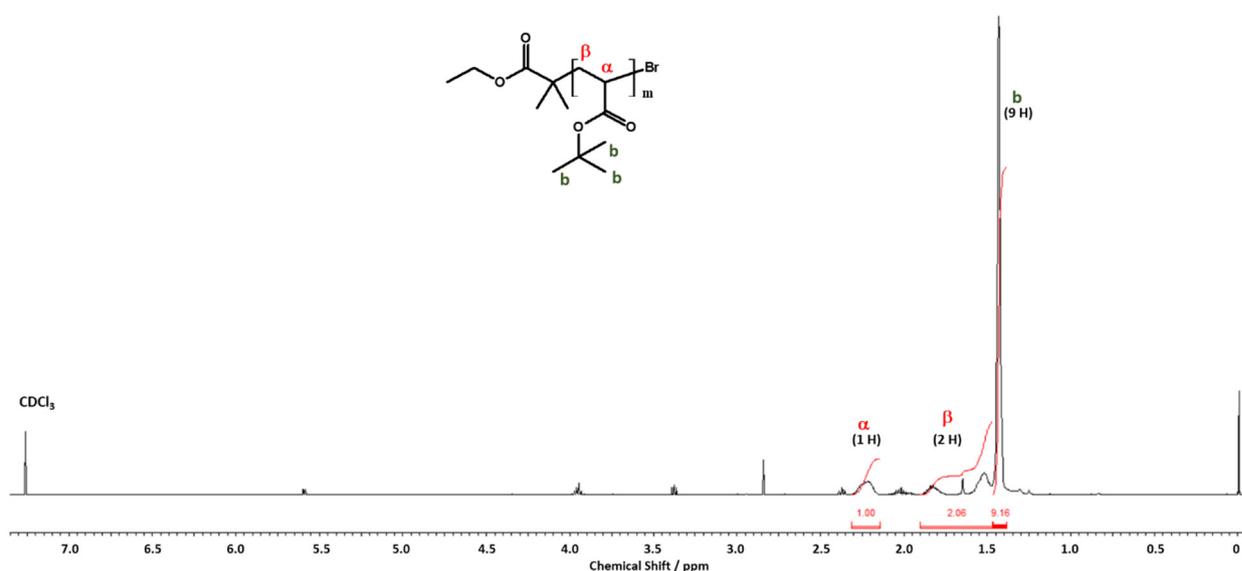


Figure S10. ^1H NMR spectrum of PBA homopolymer (Table 1, entry 4).

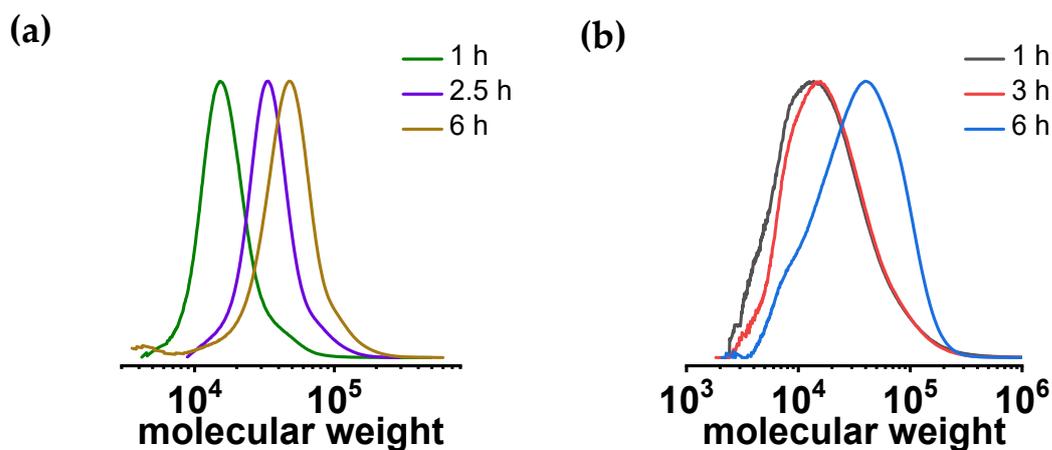


Figure S11. GPC traces of free polymers generated from sacrificial initiator during preparation of surface-grafted PHEA brushes according to (a) Table 1, entry 1 and (b) Table 1, entry 4.

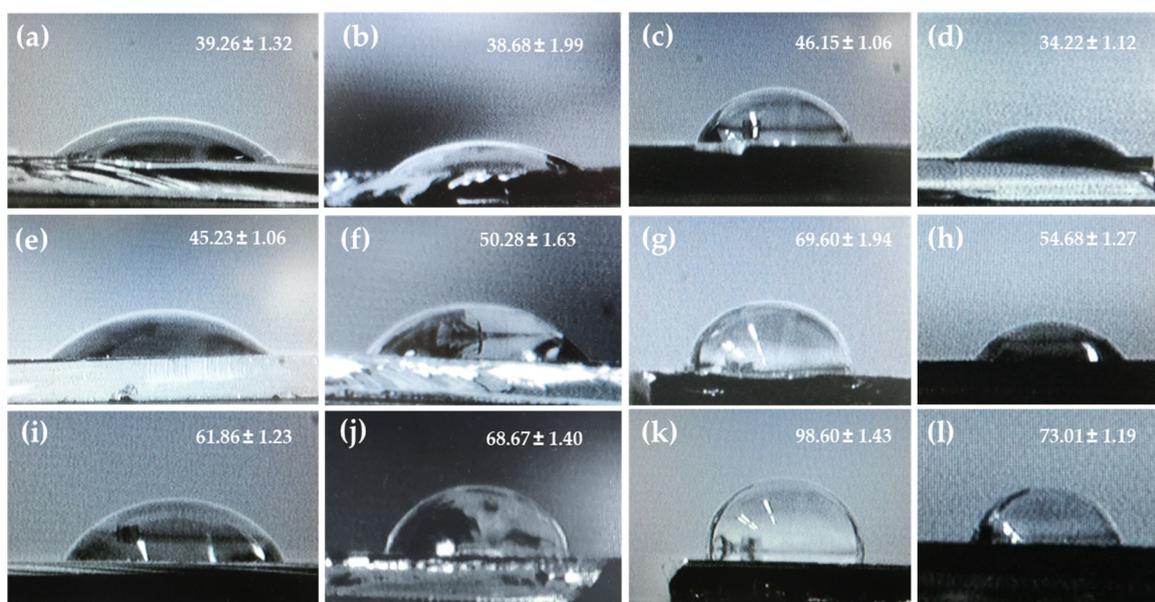


Figure S12. (a) Diiodomethane, (e) formamide and (i) water contact angle images of Si-g-PHEA prepared according to Table 1 (entry 1), (b) diiodomethane, (f) formamide and (j) water contact angle images of Si-g-PHEA prepared according to Table 1 (entry 2), (c) diiodomethane, (g) formamide and (k) water contact angle images of Si-g-(PHEA-*b*-PtBA) prepared according to Table 1 (entry 4) and (d) diiodomethane, (h) formamide and (l) water contact angle images of Si-Br.

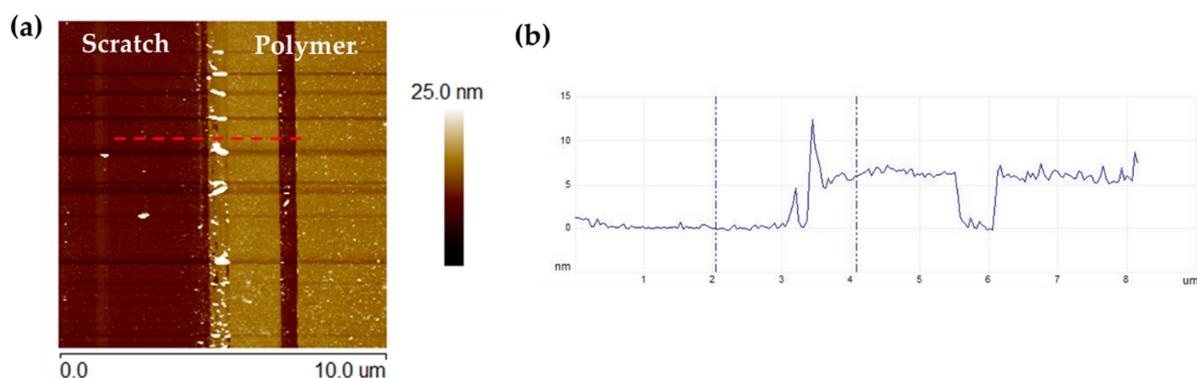


Figure S13. AFM analysis of well-defined polymer brushes grafted from silicon wafers. Height image of PHEA (a) according to Table 1, entry 3, (b) cross-section profile captured in the place marked with a red dotted line in the topography image, (Table 1, entry 3).

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